

# CONTROLLING DARK CURRENT IN TYPE-II SUPERLATTICE PHOTODIODES



## Quantum Structures Infrared Photodetectors (21 January 2009, Yosemite CA)

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## ***OUTLINE***

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- LWIR detection – Why so challenging, & what key parameters can we improve with electronic & optical engineering?
- “W”-superlattice absorber for LWIR photodiodes
- Graded-gap “W” for LWIR photodiodes
- Hybrid Photodiodes : TSL/GG-W
- Suppression of surface currents
  - Self-passivation by GG-W
  - Shallow-Etch Mesa Isolation (SEMI)



# CHALLENGES OF LONG $\lambda$ DETECTION

- Significant challenges in growth/processing of MCT and ABSLs
- Short lifetime (for thermal generation)
- Large thermal population

$$D^* \propto QE/j_D^{1/2} \quad QE \approx L_d \alpha^{(1)} / (L \alpha + 1)$$

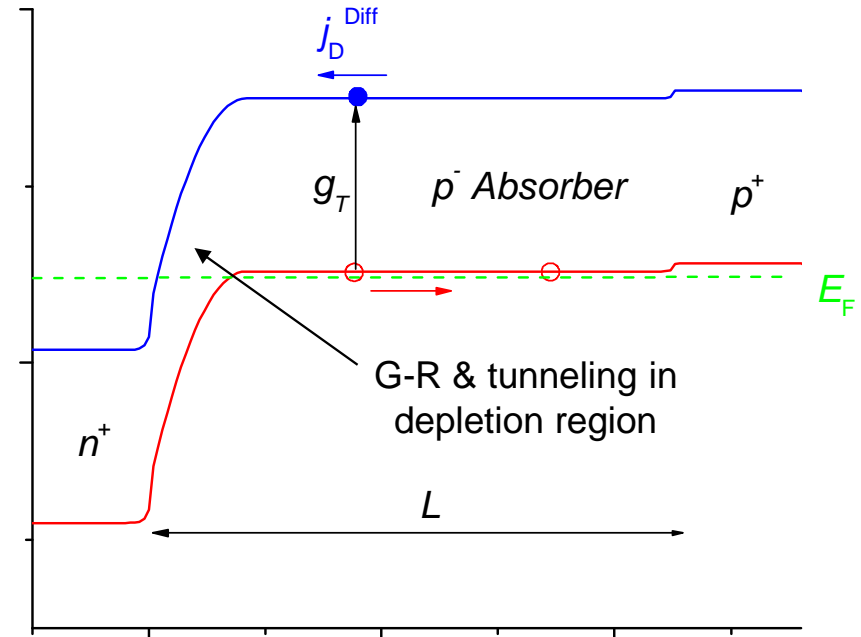
$$L_d = (D \tau)^{(3)} \quad D = k_B T \mu^{(2)} / q$$

$$j_D \approx j_D^{Diffusion} + j_D^{GR} + j_D^{Tun} + j_D^{Sidewall}$$

$$E.g.: j_D^{Diff} = qLg_T \rightarrow qLn_i^2/N_A \tau^{(3)}$$

$$n_i^2 = N_c N_v \exp(-E_g/k_B T)^{(4)}$$

At 300 K:  $>10^{18}$  worse @  $10 \mu m$  than  $1 \mu m$ !



Keys to improved performance:

- $L_d \alpha > L \alpha > 1$  for high QE
- Maximize: ①  $\alpha$ , ②  $\mu$ , ③  $\tau$ , & ④  $E_g$

Because thermal generation rate scales exponentially with  $E_g$ , detection is many orders of magnitude more challenging in LWIR than NIR

G-R & tunneling currents also scale exponentially with  $E_g$ , as does sidewall leakage



# DIFFUSION CURRENT: MAXIMIZE LIFETIME

$$j_D^{\text{Diffusion}} = qLg_T \rightarrow qLn_i^2/N_a\tau$$

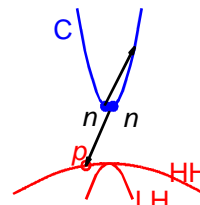
$$n_i^2 = N_c N_v \exp(-E_g/k_B T)$$

Small  $E_g$  in absorber is fixed by  $\lambda_{co}$  – So at least maximize  $\tau$

Long lifetime minimizes thermal generation rate  
(& also maximizes diffusion length for high QE)

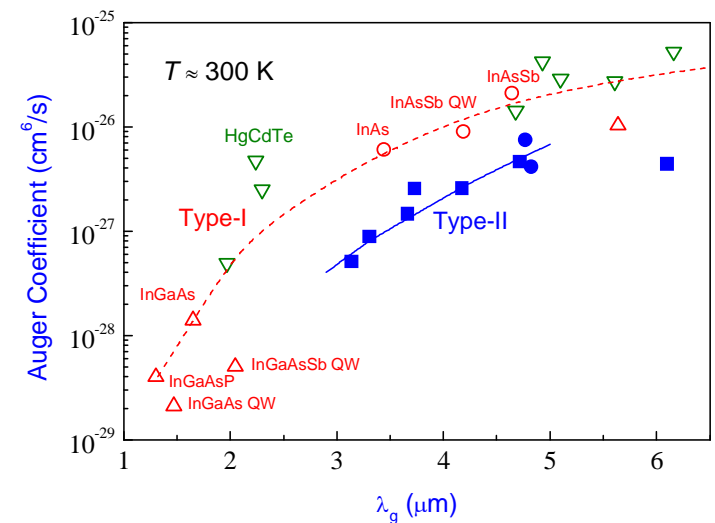
- Auger lifetime:** Enhance with band-structure engineering

- CCCH processes strongly suppressed because  $m_n \approx m_p$



- Eliminate valence intersubband resonances to suppress CHHH & CHHL (Easier said than done – Band parameters not sufficiently well known)

- If further suppression is possible, ternary offers more flexibility than binary (whereas growth quality may favor binary)



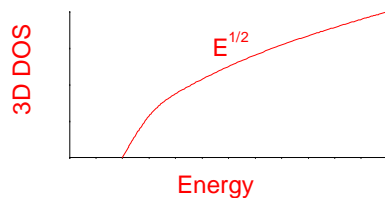
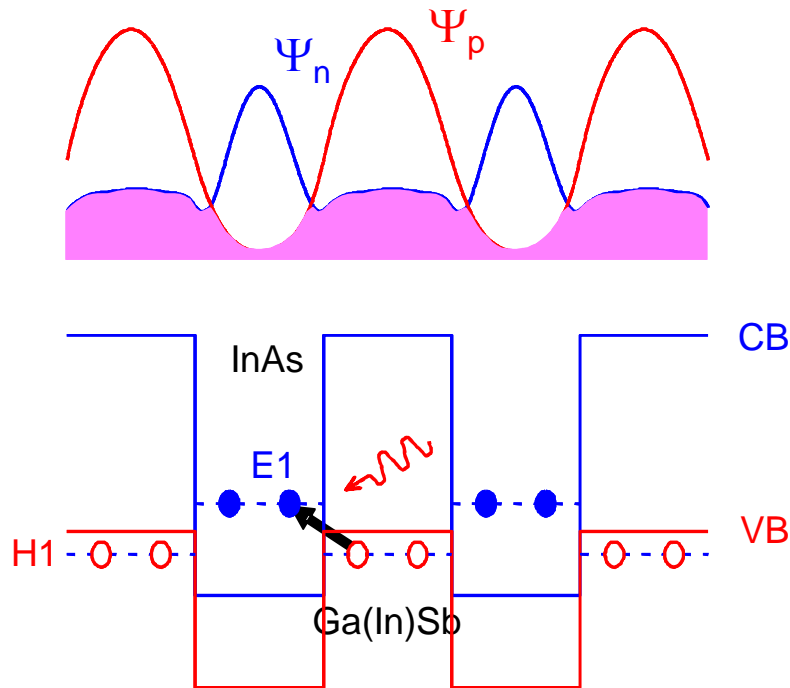
- Shockley-Read lifetime (typically 10-100 ns):** Key is high MBE quality



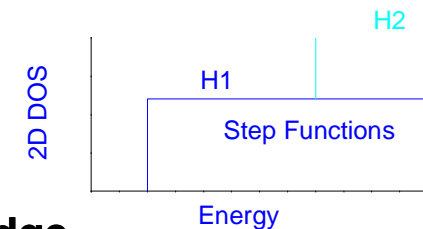
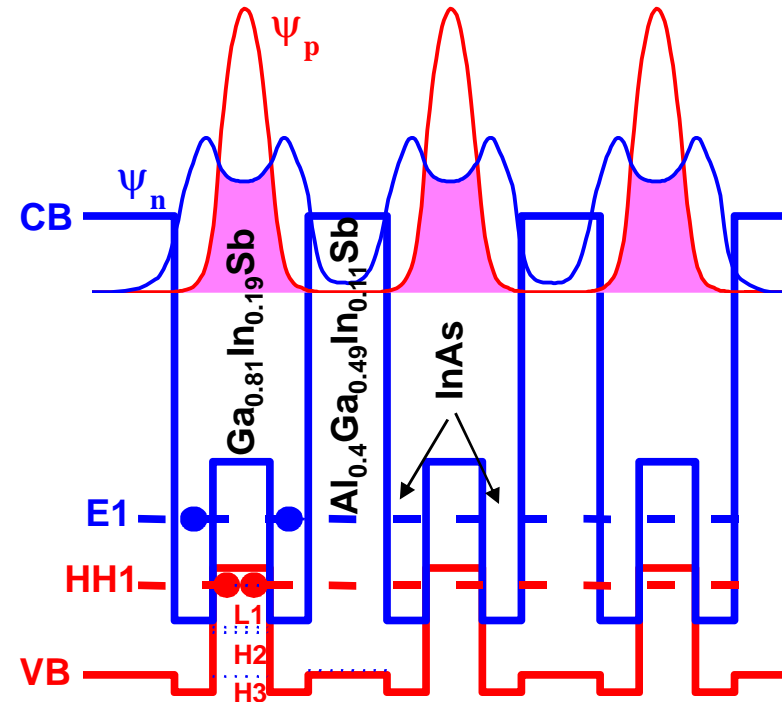
# ANTIMONIDE “W” DETECTORS

*Aifer et al., APL 89, 053519 (2006)*

## Type II Superlattice (T2SL)



## Type-II “W” Superlattice (WSL)



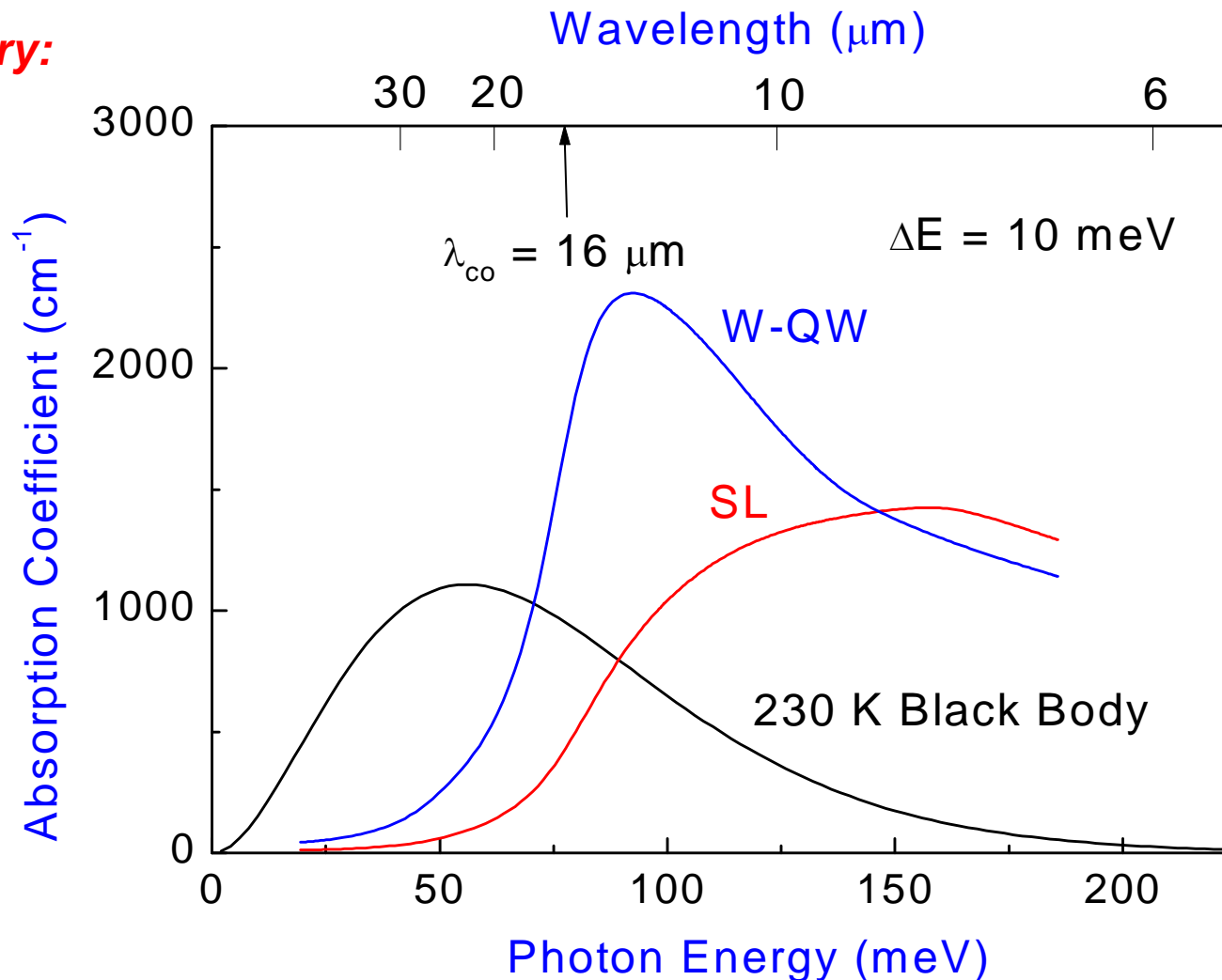
### Primary advantages:

- (A). 2D DOS for more abrupt absorption edge
- (B). Heavier mass for tunneling suppression
- (C). Flexible independent control over CBO & VBO



## (A). LARGE DOS FOR STRONG ABSORPTION

**Theory:**



***W-QW has much sharper absorption edge than superlattice (Must be careful, because absorption over broad band often more relevant than just at band edge)***

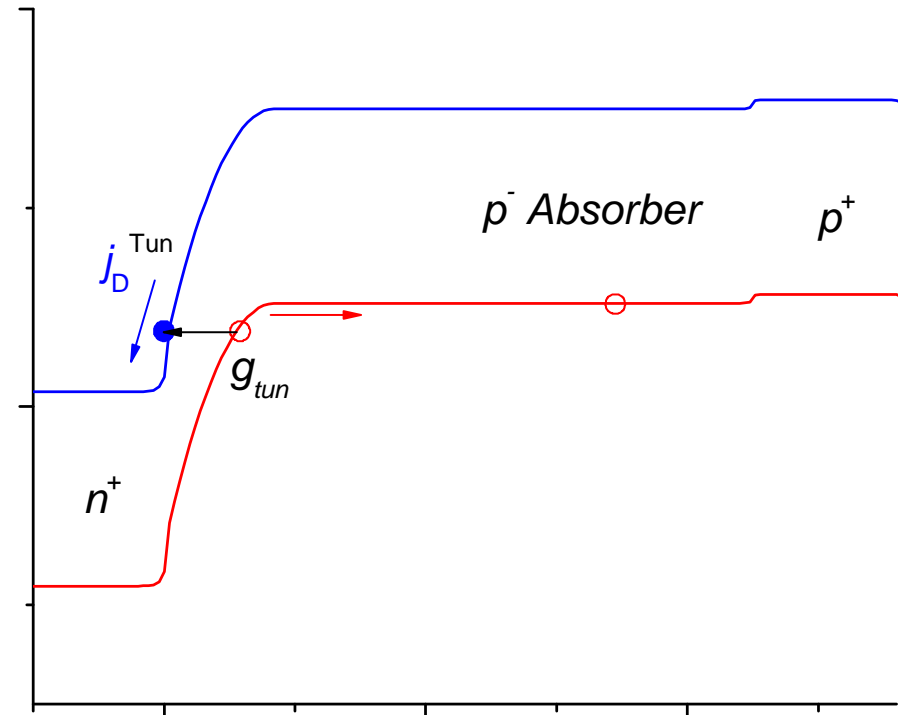


## (B). TUNNELING SUPPRESSION

$$j_D^{tun} \propto g_{tun} \propto (m_r/E_g)^{1/2} \exp(-Cm_r^{1/2} E_g^{3/2})$$

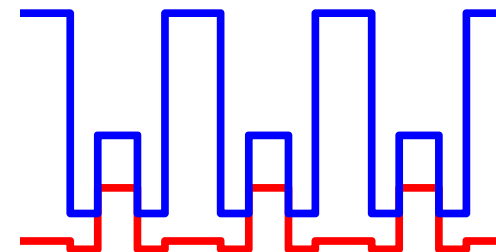
Similar for trap-assisted tunneling, but worse because:

$$E_g \rightarrow E_g - E_t$$



InAs/Ga(In)Sb SL typically has  
3 x larger electron mass than HgCdTe

Mass in “W” SL much larger than that, tunable  
with barrier thickness

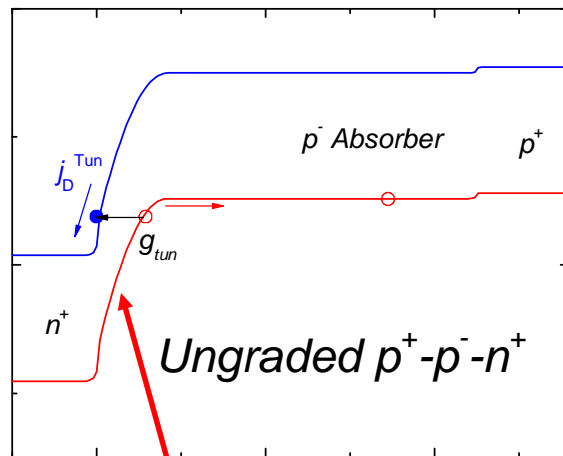


*But we can do better!*

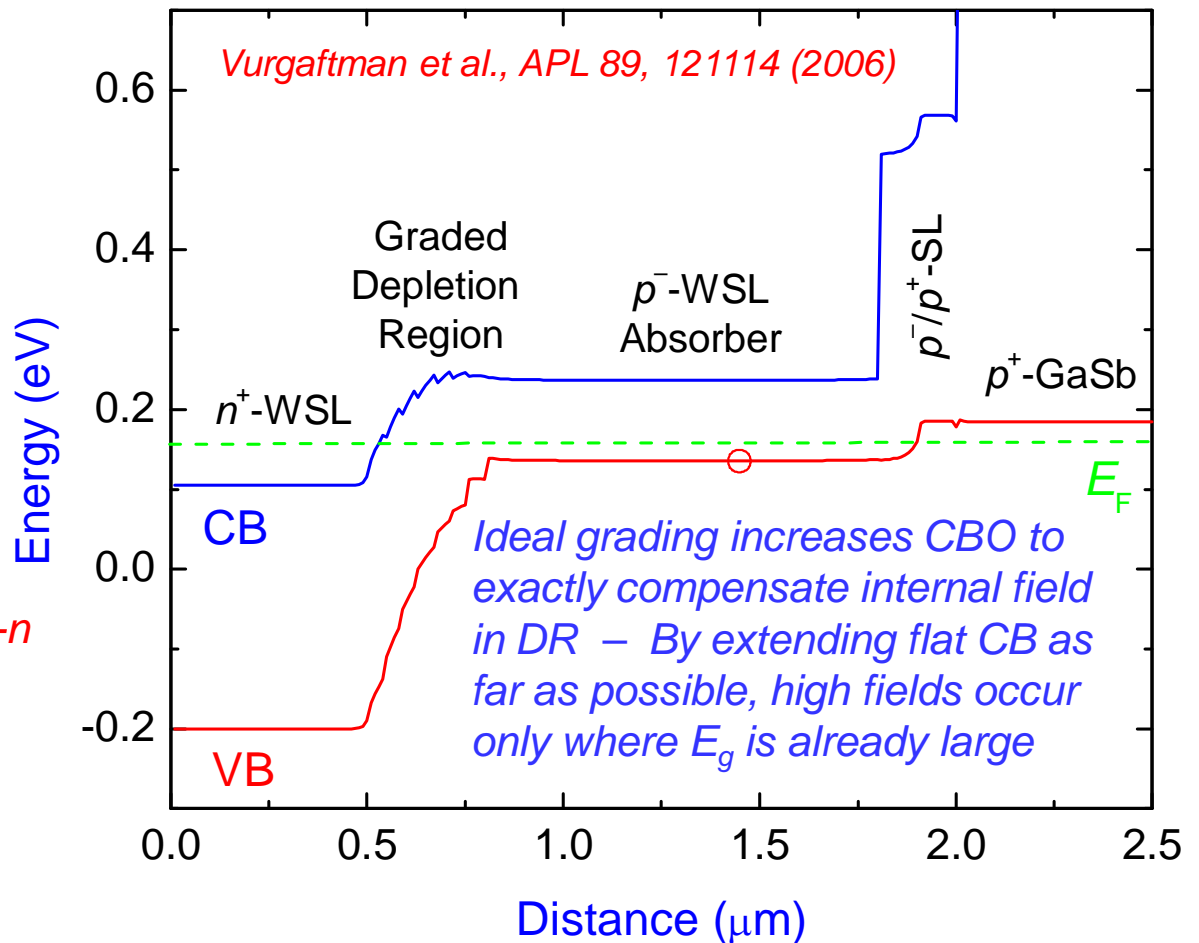


## “W” WITH GRADED-GAP DEPLETION REGION

Need to have a small gap in absorber, *but not everywhere* – Since abrupt shift of  $E_g$  would induce large barrier to minority-carrier extraction, *grade the depletion region*:



- Depletion region of ungraded p-i-n has very high internal fields (mid- $10^4$  V/cm) – Induces excessive tunneling & G-R
- Grading transfers high fields to larger-gap region





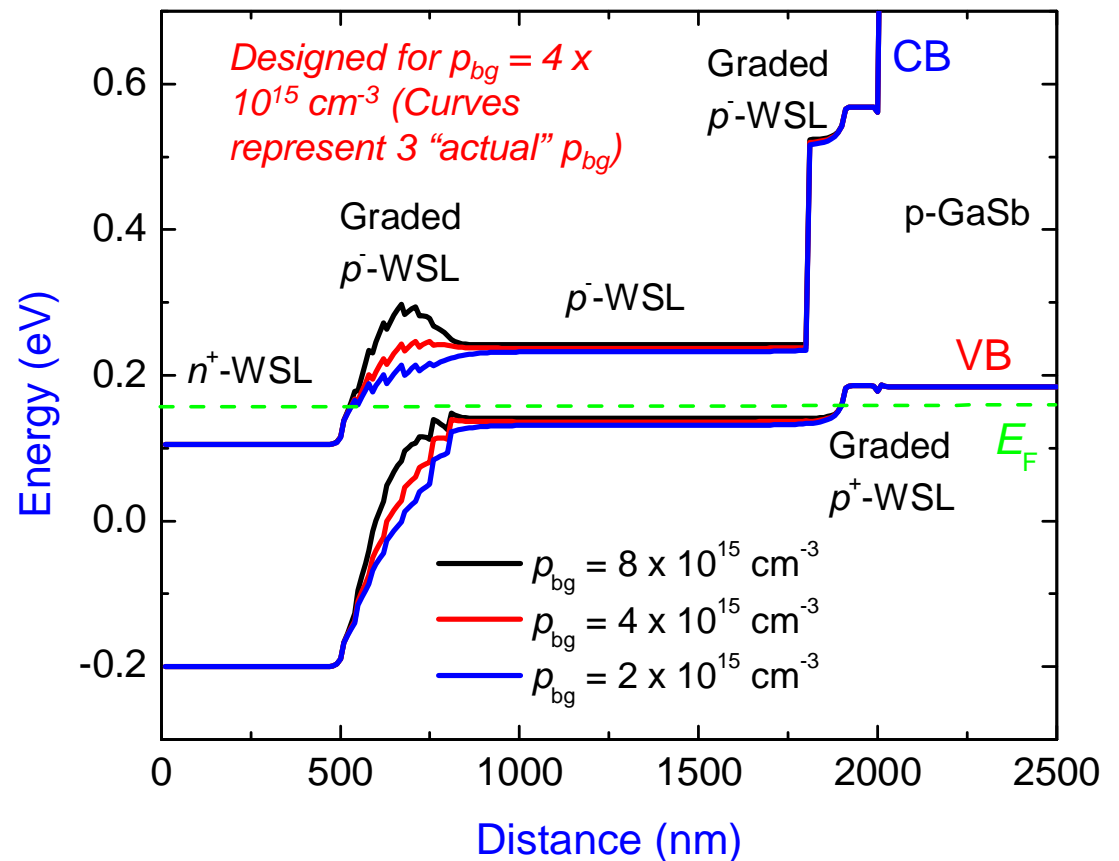


# GRADING PROFILES

Grading should compensate internal field in depletion region, which is determined by unintentional background  $p^-$  doping level ( $p_{bg}$ )

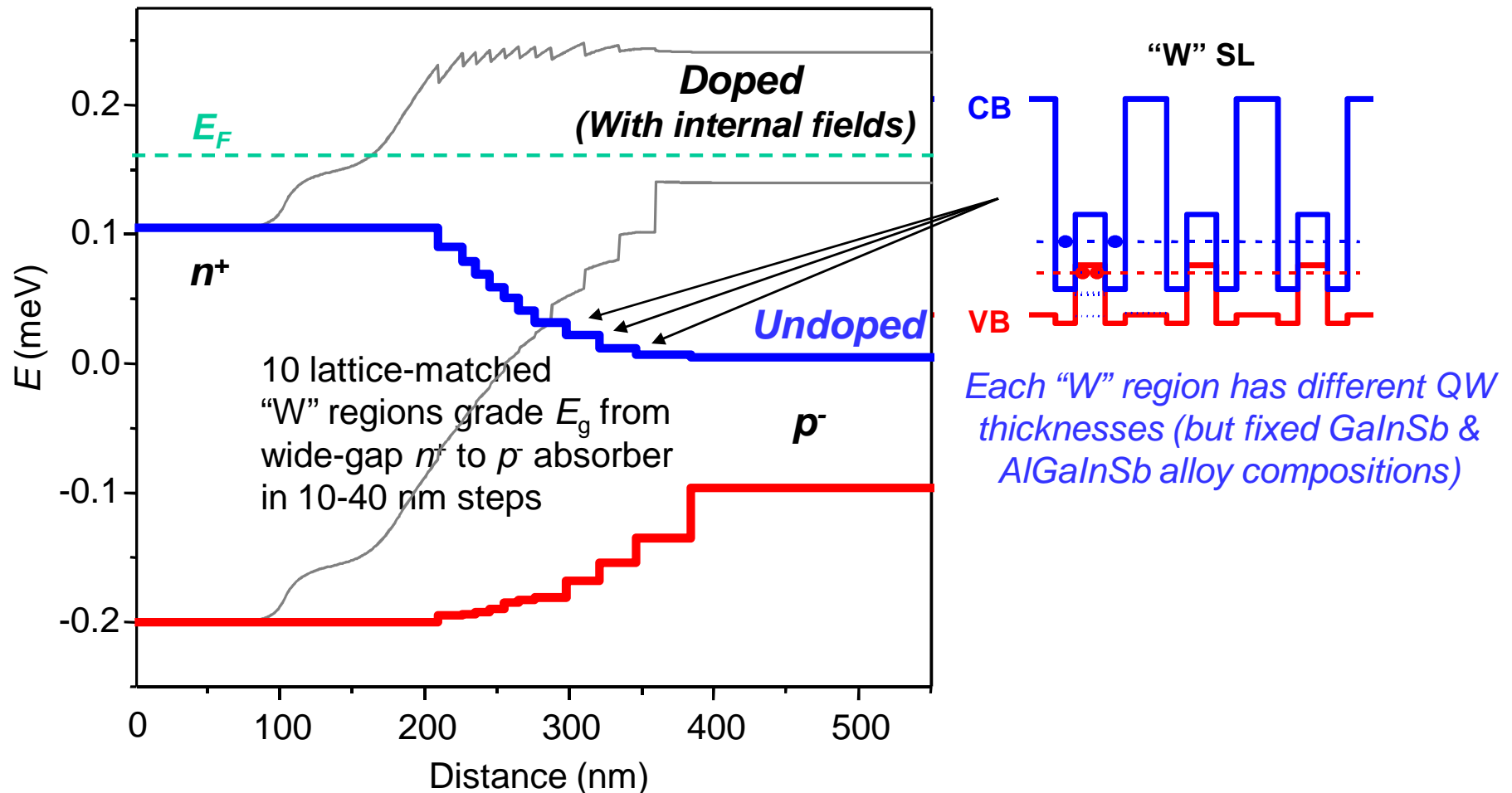
If design **underestimates** actual  $p_{bg}$ , induced barrier blocks collection of photoexcited electrons until reverse bias is applied

If design **overestimates**  $p_{bg}$ , CB slopes too soon & narrow gap sees high internal field





## (C). INDEPENDENT CONTROL OVER CBO & VBO



- 3 knobs (InAs, GaInSb, & AlGaInSb thicknesses) allow nearly independent control over CBO,  $E_g$ , & strain compensation (Impossible with 2-constituent SL or MCT)
- No need for challenging mid-growth variations of alloy composition



# Graded-Gap “W” Photodiode for Long-Wave Infrared Detection

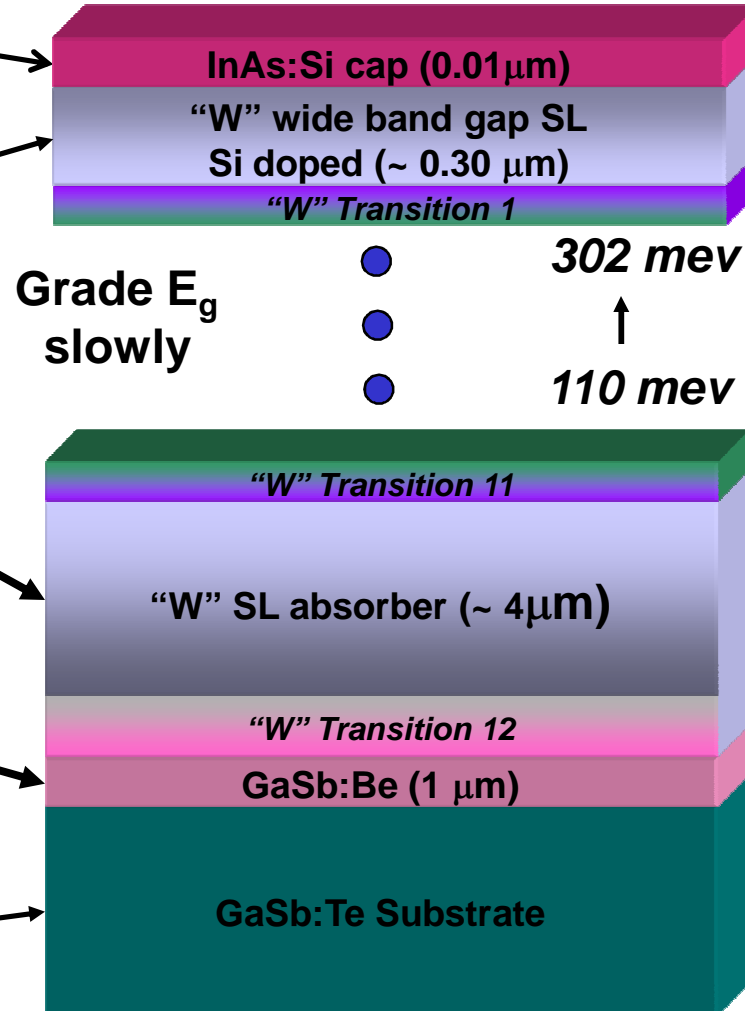
***N<sup>+</sup> capping layer***

***Wide bandgap “W” n-region***

***Lightly doped absorber for good  $\tau$***

***Heavily doped bottom contact***

***Lightly doped substrate to minimize  $\alpha$***



$$n_{\text{Si}} \sim 4 \times 10^{17} \text{ cm}^{-3}$$

$$n_{\text{Be}} \sim 5 \times 10^{15} \text{ cm}^{-3}$$

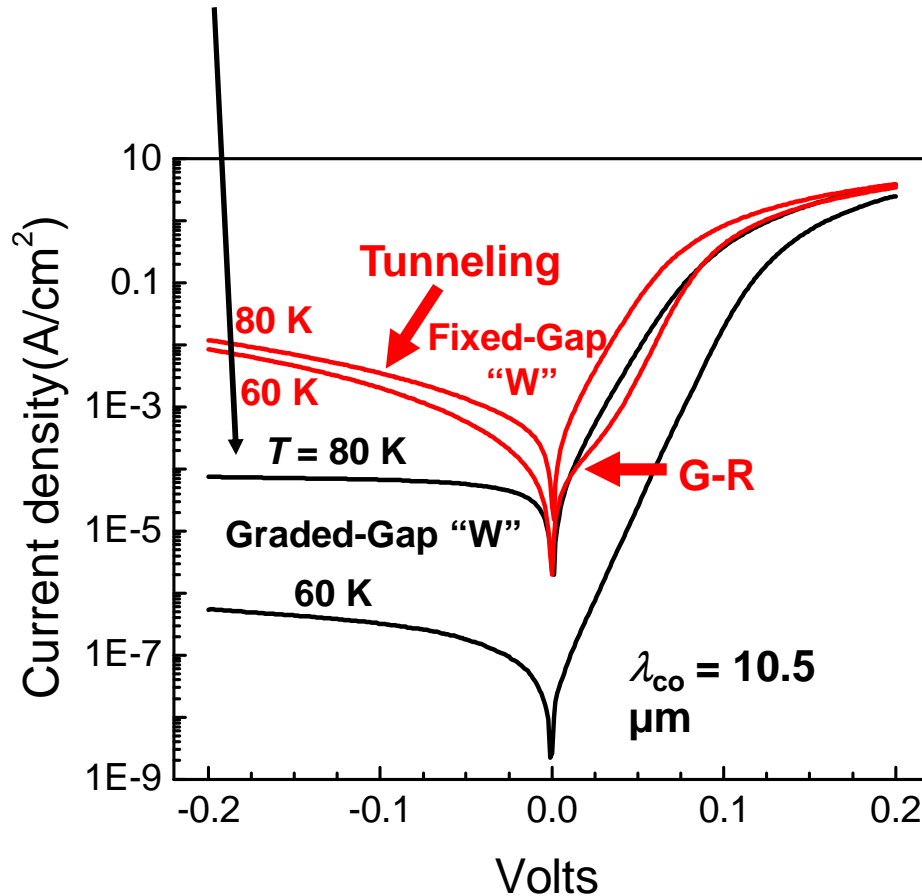
$$n_{\text{Be}} \sim 3 \times 10^{18} \text{ cm}^{-3}$$

$$n_{\text{Te}} \leq 1 \times 10^{17} \text{ cm}^{-3}$$

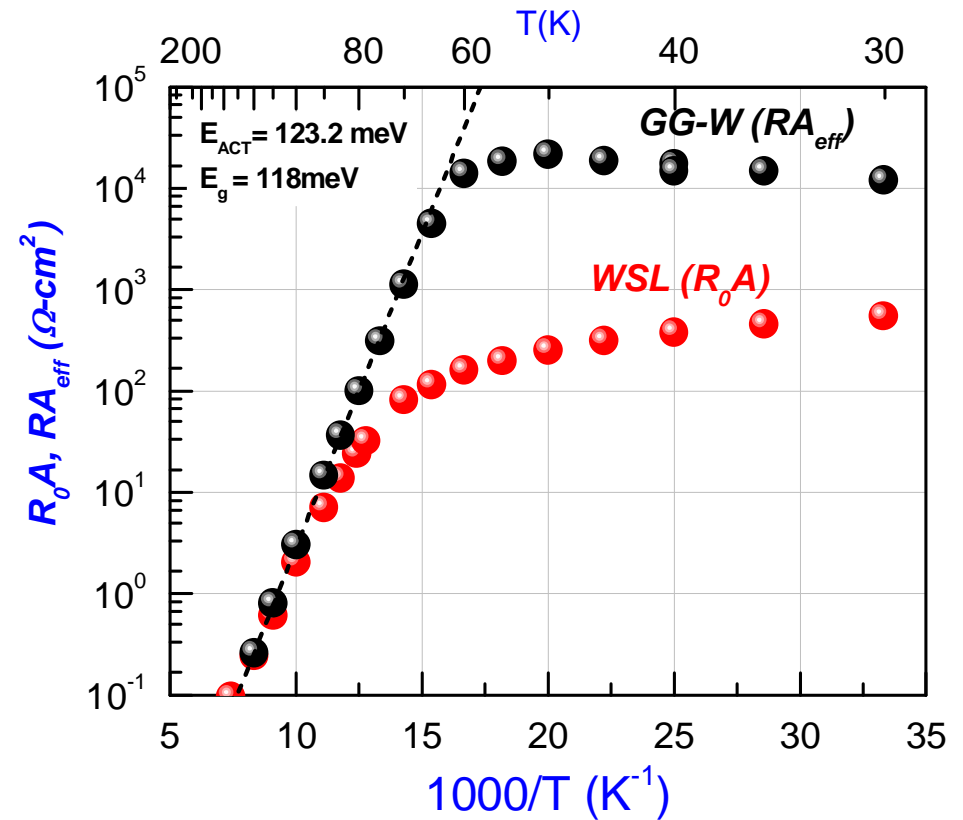


# GG-W PHOTODIODES: SUPPRESSED DARK CURRENTS & HIGH $R_0A$

Nearly-flat I-V implies strong suppression of tunneling, TAT, & G-R currents in GG-W

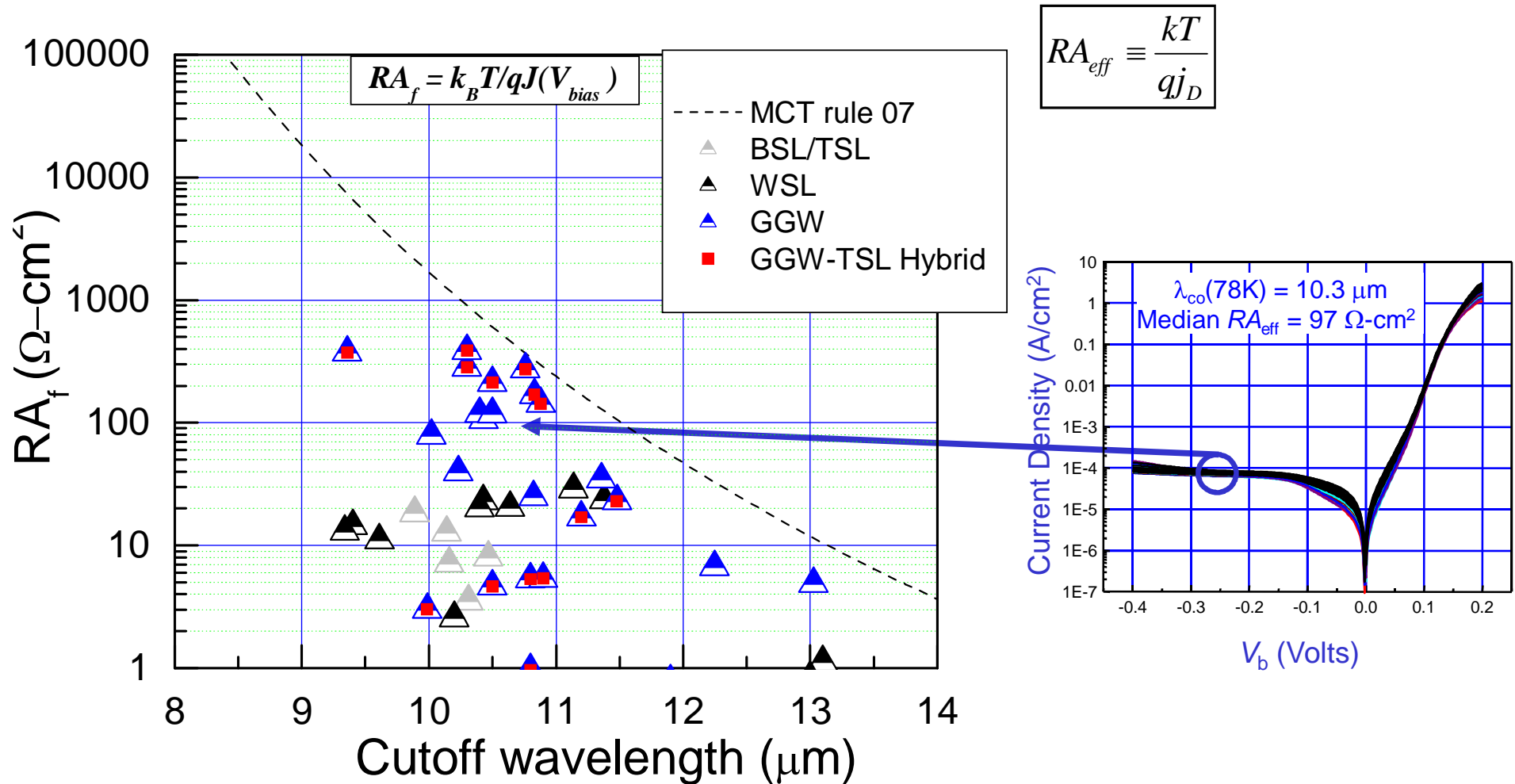


GGW diffusion limited well below 80K  
(Note use of  $RA_{eff} = k_B T / q J_{bias}$  for GG-W operating at non-zero  $V_{bias}$ )





## GG-W ( $RA_{eff}$ ) vs. MCT



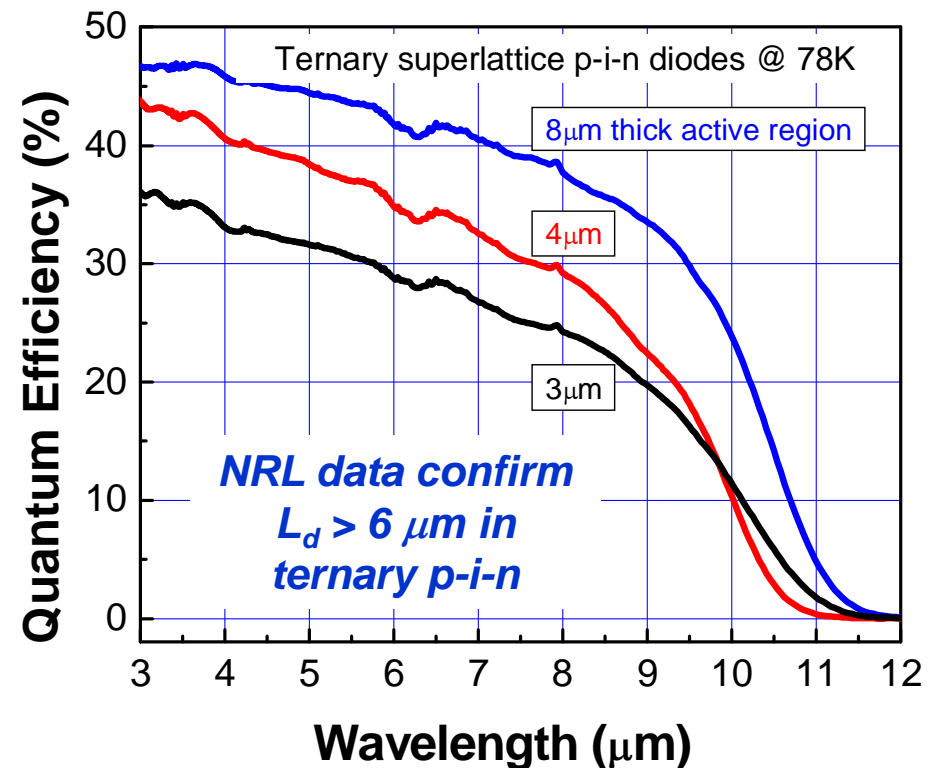
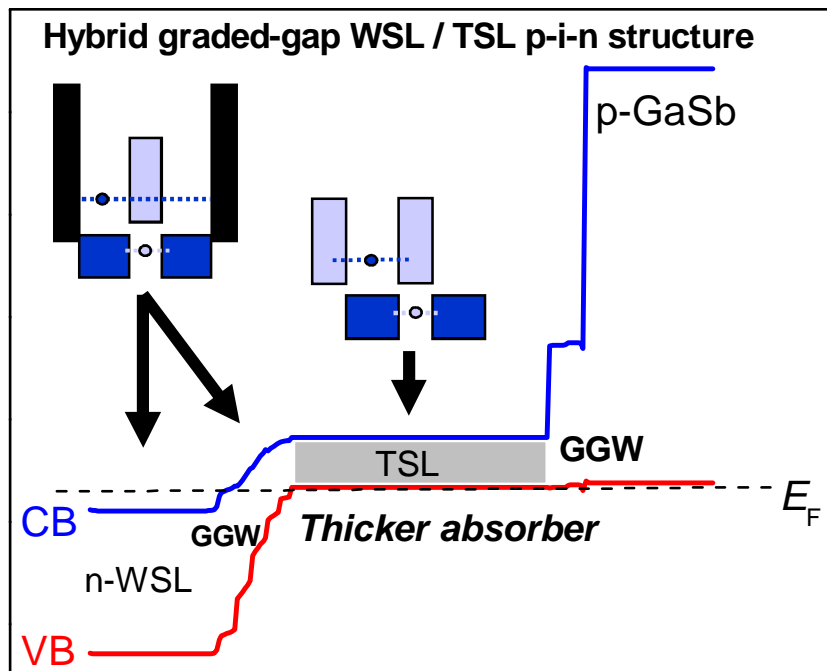
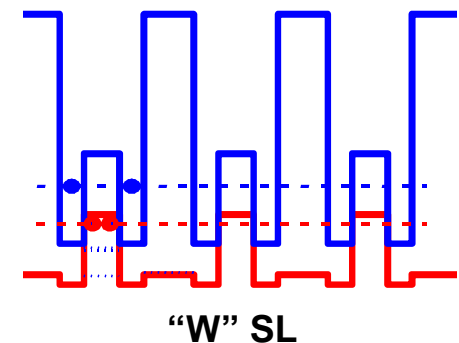
**GG-diode results approach MCT rule07 – poised to move ahead**



## “W” LIMITATION – LOWER MOBILITY

Larger  $m_{nz}$  in WSL suppresses tunneling, but with unwanted side-effect of decreasing mobility

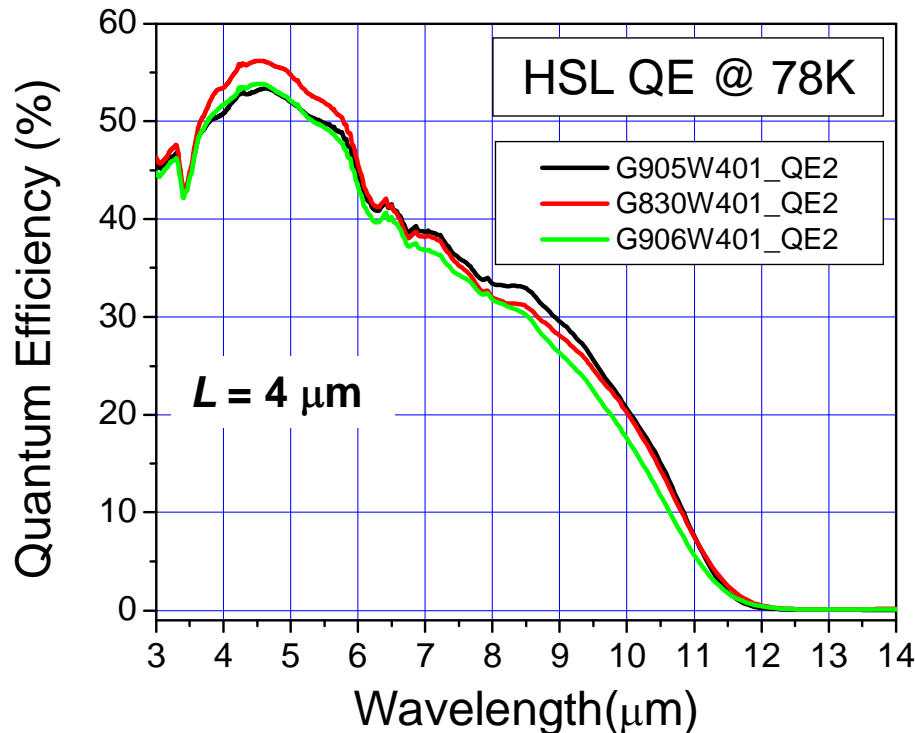
**Fix:** Hybrid, with SL absorber but GG-W depletion region (Also reduces scattering by eliminating 2 interfaces per period, & eliminates Al-containing layers)



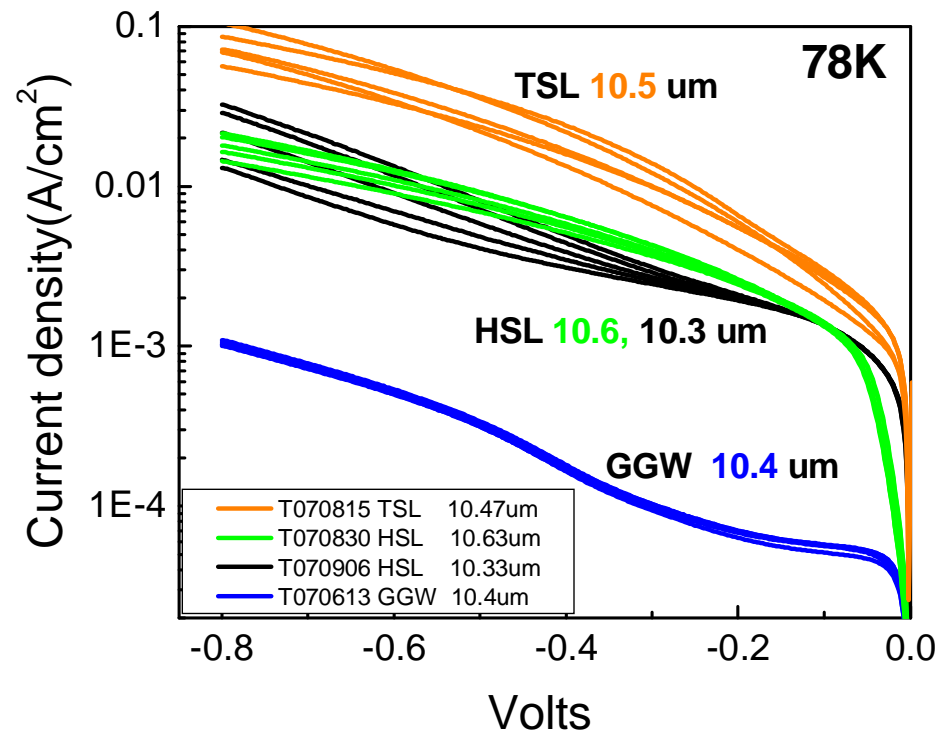


# PRELIMINARY HYBRID SL PHOTODIODES

$QE_{HSL} \sim 33\%$  at  $8\mu m$  ( $QE_{GGW} < 30\%$ )



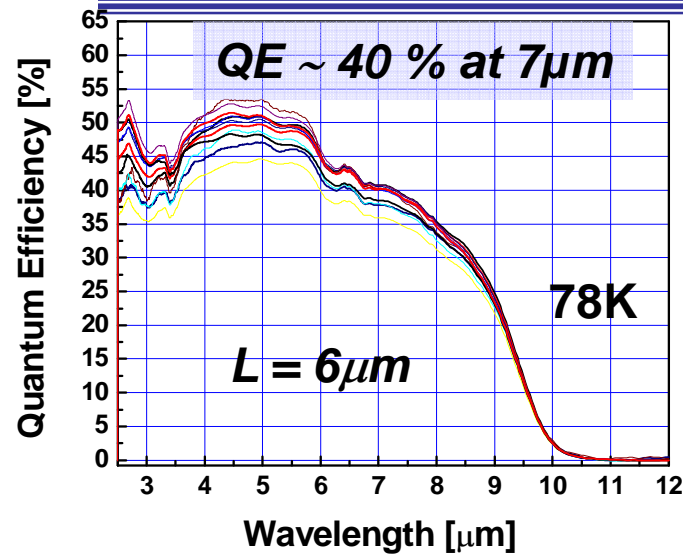
$RA_{eff}(HSL) \sim 10 \Omega\text{-cm}^2$   
(factor of 10 lower than GG-W)



Initial hybrid structures yield higher QE than GG-W & lower dark current than TSLs, however QE is only marginally better and dark current characteristics inferior to GG-W

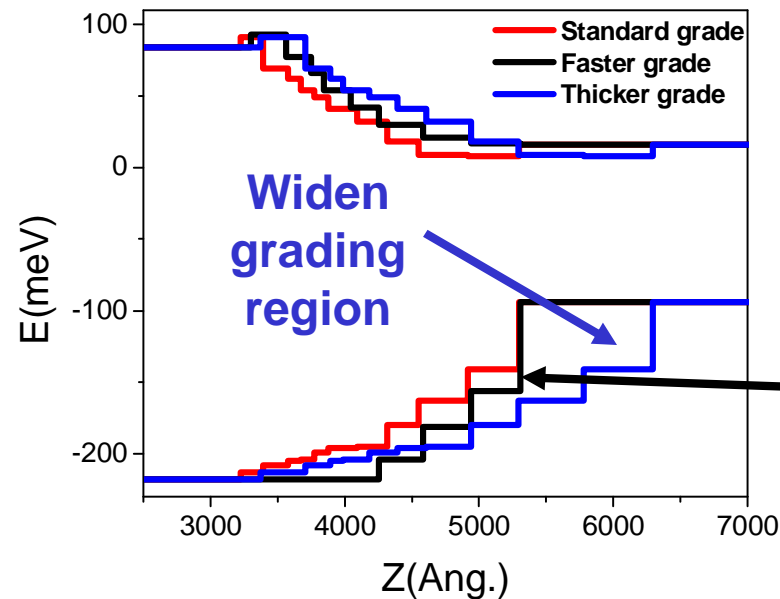
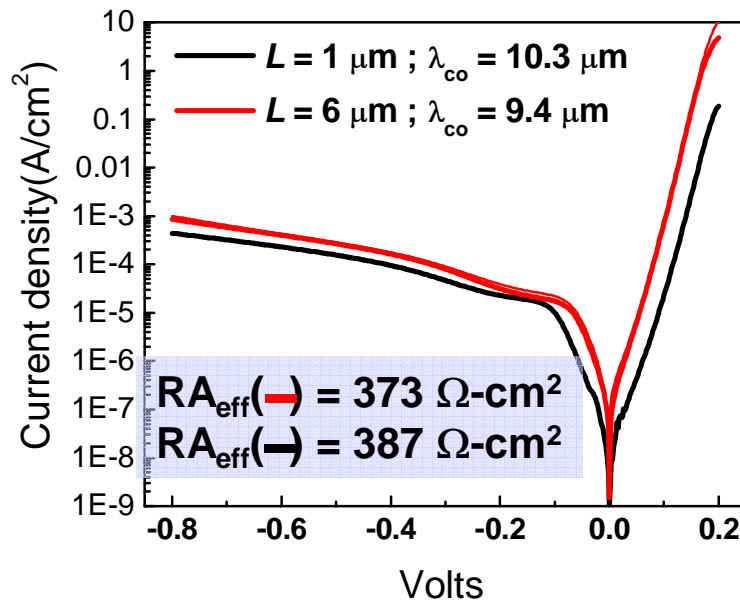


# RECENT HYBRID SL PHOTODIODES



Recent hybrid structures also yield higher QE than GG-W with improved dark current characteristics due to improved designs

Thicker hole well in SL and refinement of bandgap grading for HSL



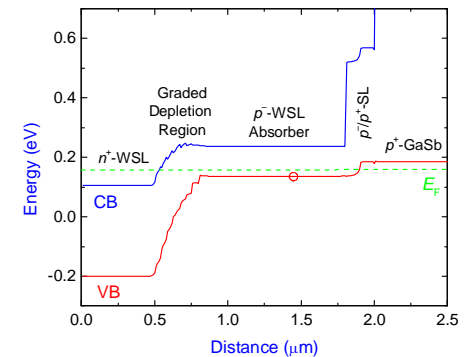
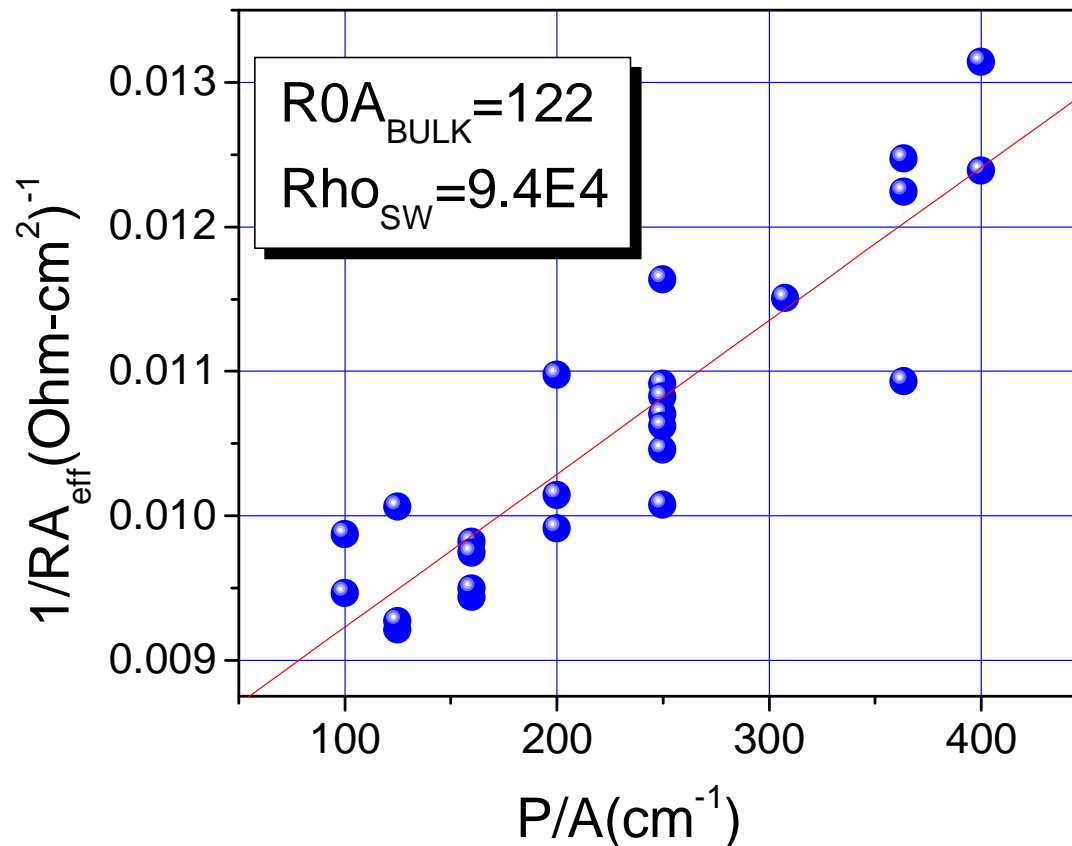
Push VB down more quickly





# SURFACE CURRENT: SELF-PASSIVATION IN GG-W

Sidewall resistivity extracted from  $R_0A$  dependence on Perimeter/Area ratio  
( $D = 100\text{-}400\ \mu\text{m}$ )



$\rho_{\text{surface}} = 4200 - 450,000\ \Omega\text{-cm}$  higher than for ANY earlier LWIR T2 results  
(both passivated & unpassivated), indicating self-passivation in GG-WSLs

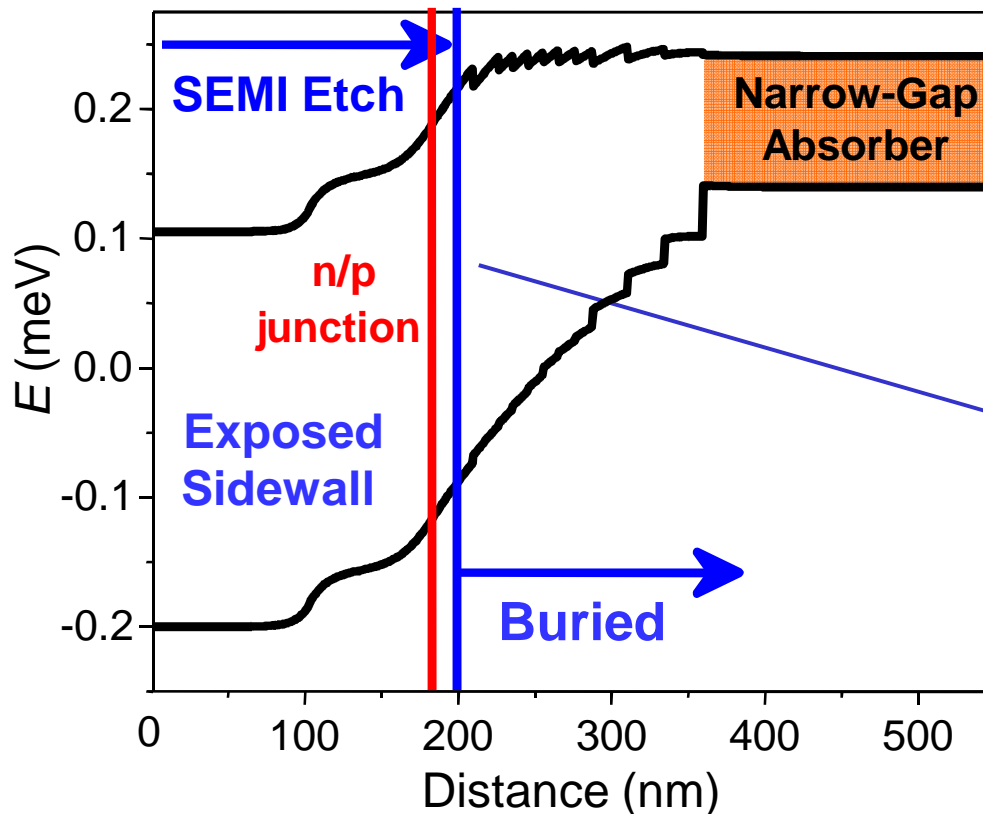
**But it's not enough**



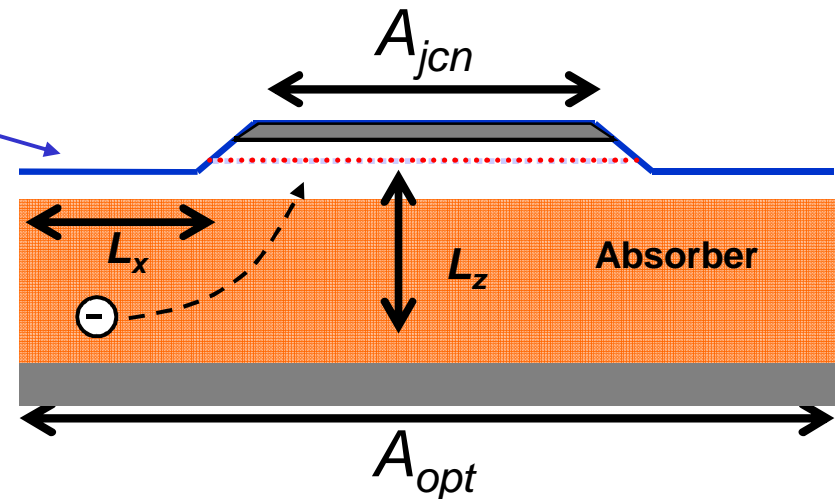
## LOWERING THE PASSIVATION BAR: SHALLOW-ETCH MESA ISOLATION (SEMI)

SEMI process, combined with GG-material, completely eliminates all exposure of narrow-gap regions to sidewalls

Passivation of wider-gap material much less challenging



*SEMI also allows 100% optical fill factor combined with reduced junction area, by relying on lateral diffusion of photoexcited carriers*

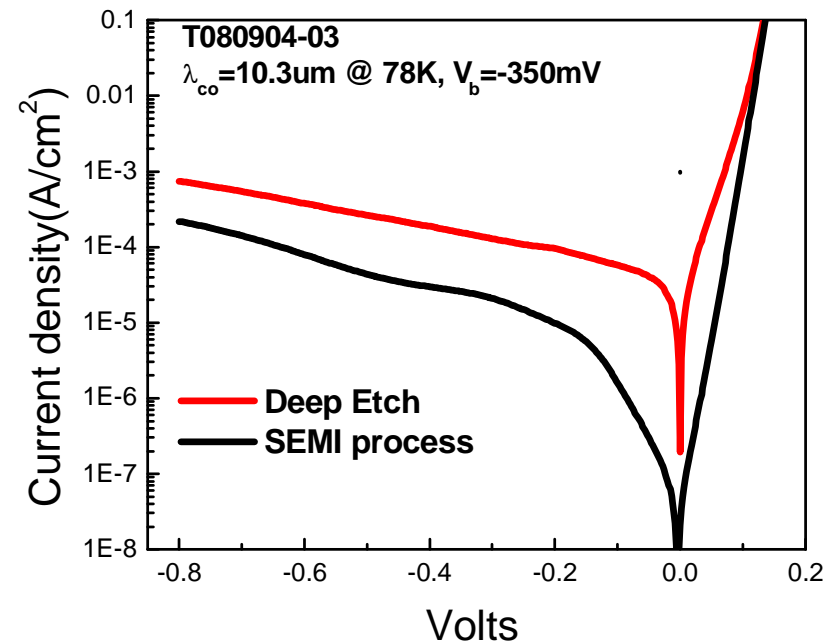
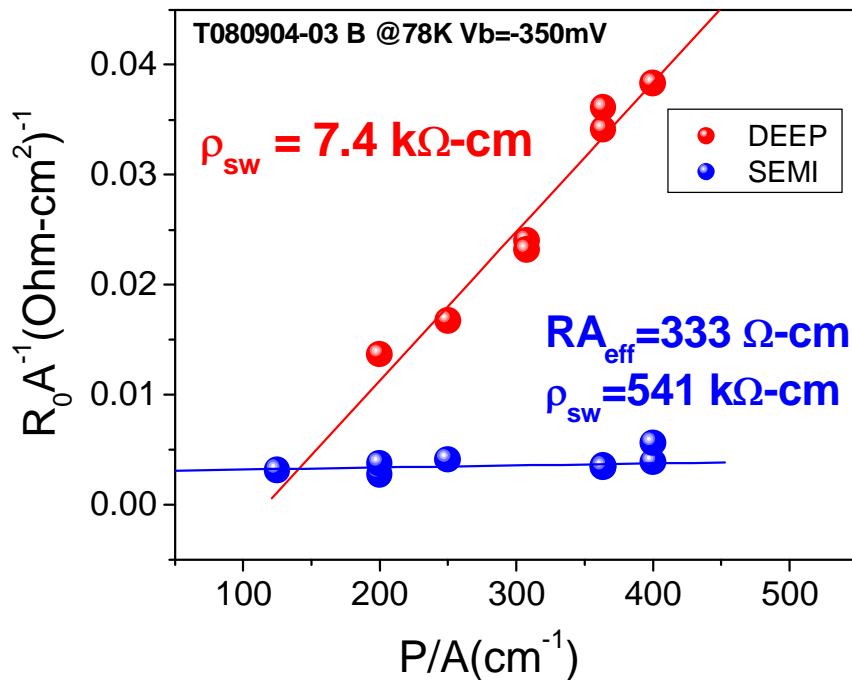
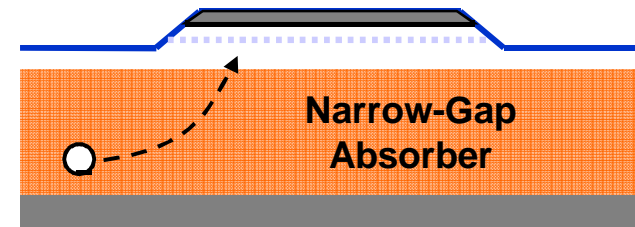




## SEMI: EFFECTIVE SELF-PASSIVATION

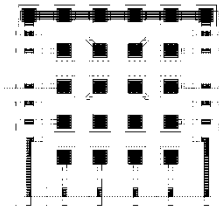
Burying the narrow-gap region substantially increases the sidewall resistivity

HSL photodetector with  $L = 1 \mu\text{m}$





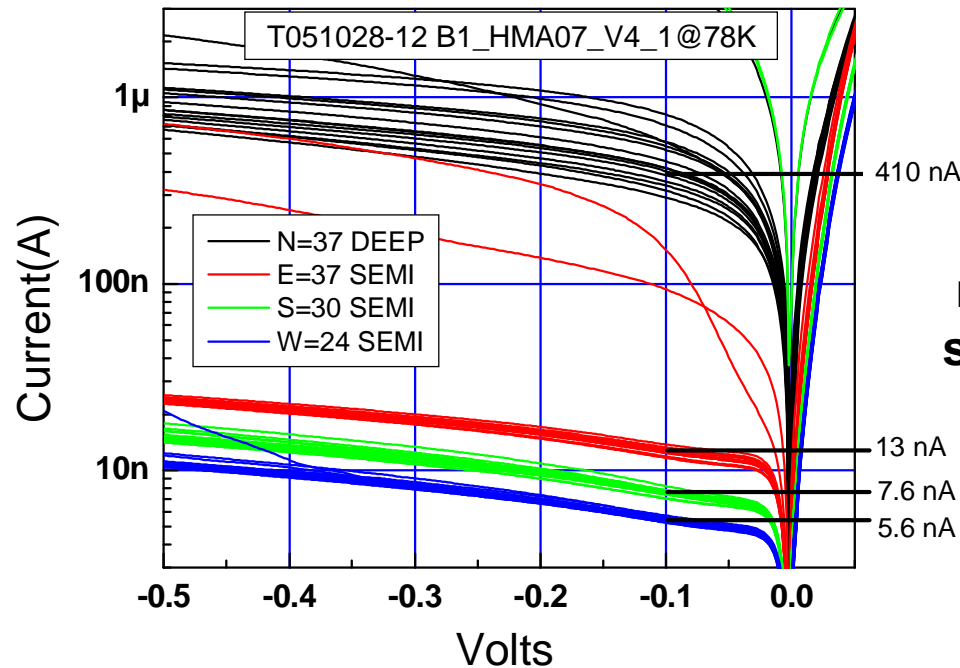
# SEMI MINI-ARRAYS: LOWER SIDEWALL CURRENTS



**4x4 Mini-Arrays**  
(40- $\mu\text{m}$  pitch, Variable junction area)

process	Lmesa( $\mu\text{m}$ )	Amesa	Rmesa	Ipix(nA)	Ri
Deep	37	1369	1.0	410	31.5
SEMI	37	1369	1.0	13	1.0
SEMI	30	900	0.7	7.6	0.6
SEMI	24	576	0.4	5.6	0.4

**SEMI dark current scales with junction area, while deep-etched array has much larger  $j_D$**



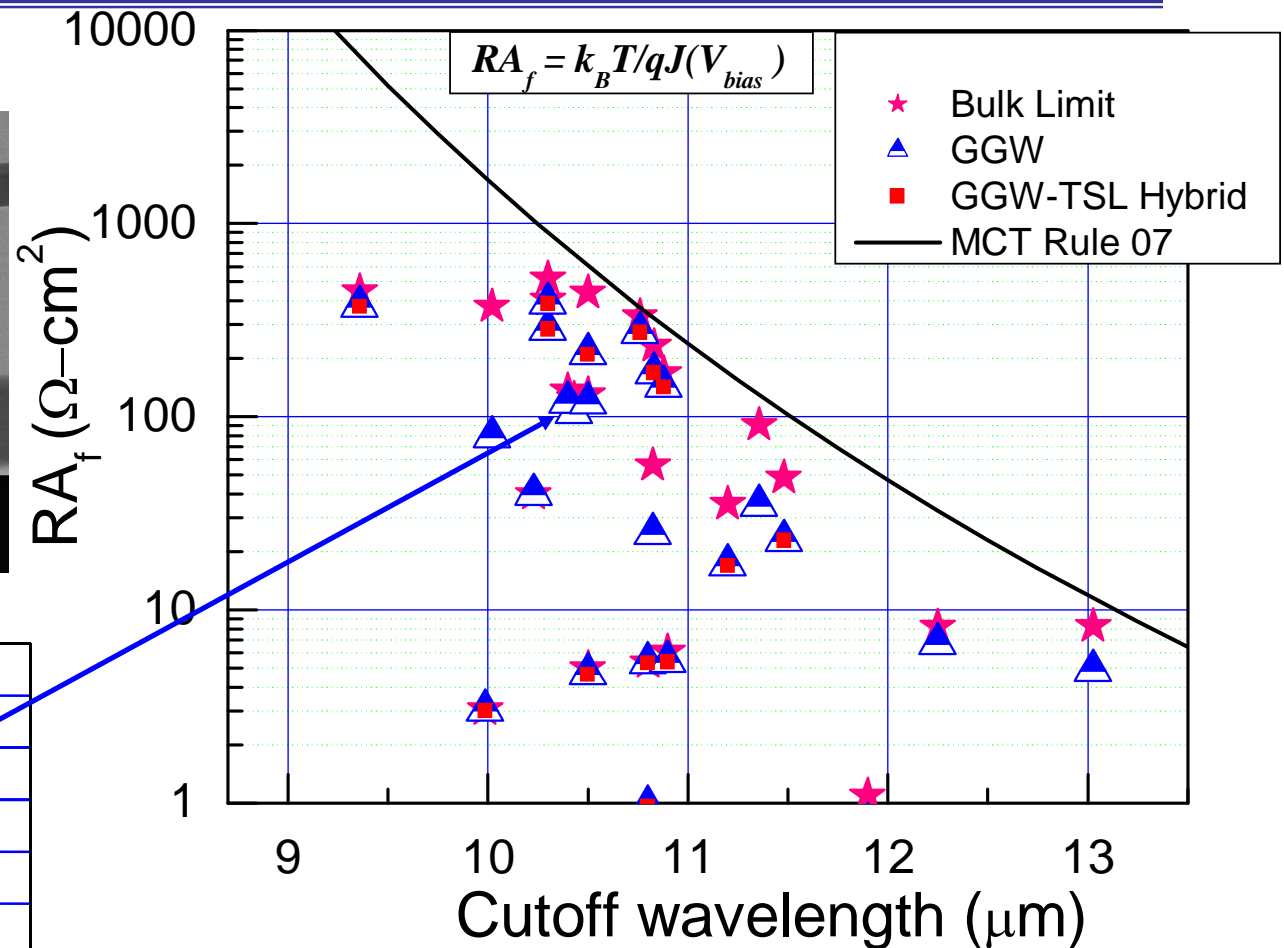
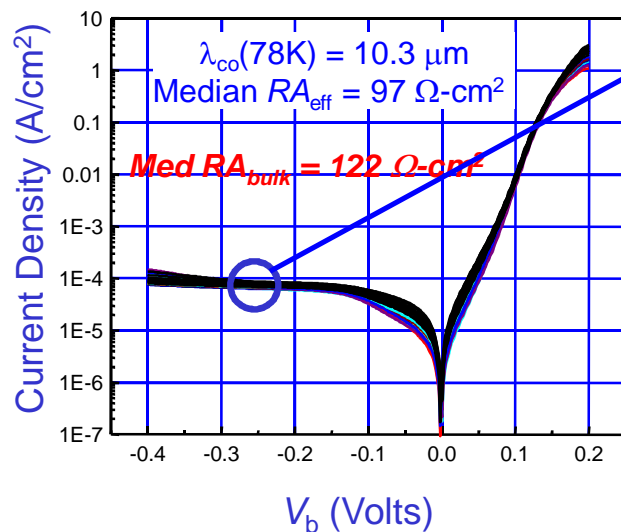
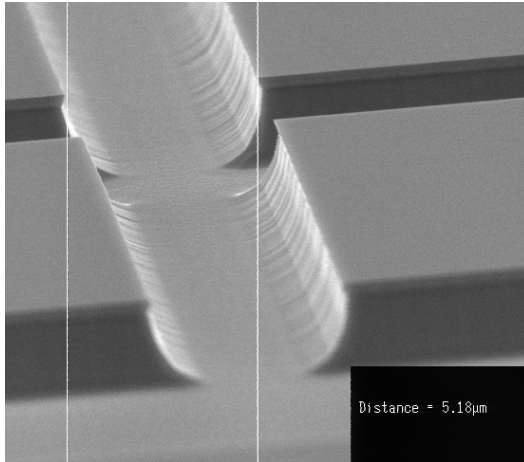
**SEMI array shows 30x dark-current reduction vs. deep-etched array with same junction area (from same wafer)**

*Also greater stability of characteristics over time*



# GG-structures – SEMI AND BULK LIMIT

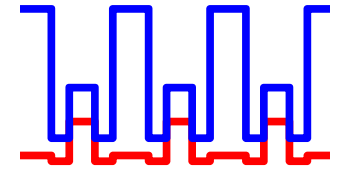
**Exposed mesa sidewalls**



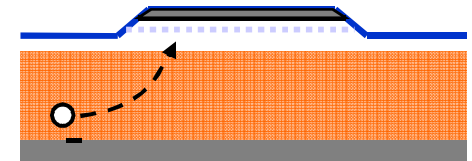
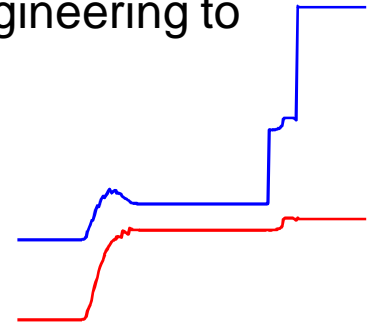
**Using SEMI to suppress surface leakage  
then push further with graded doping in  
absorber for reduced  $J_D$**



## SUMMARY



- Long- $\lambda$  detection is orders of magnitude more challenging – For best  $D^*$ , maximize QE & minimize various dark currents by using electronic/optical engineering to enhance: (1) absorption, (2) mobility, (3) lifetime, & (4) energy gap
- “W” SL combines 2D DOS for high  $\alpha$ , large  $m_{nz}$  for suppressed tunneling, & flexible independent control over CBO & VBO
- Graded-gap “W” strongly suppresses tunneling & G-R currents
- Hybrid (SL absorber + GG-W depletion region) enhances QE ( $L_d \geq 6 \mu\text{m}$ ) yet maintains good dark current characteristics
- Surface currents reduced:
  - (1) Increased  $E_g$  in depletion region of GG-diodes provides self-passivation
  - (2) Shallow-Etch Mesa Isolation (SEMI) + GG-diodes
    - Eliminates all narrow-gap exposure to etched sidewalls
    - Reduces junction area while maintaining 100% fill factor
    - Mini-array testing: Far lower surface dark currents (sometimes) & greater temporal stability than conventional deep etch



**To beat MCT, still need to put all the pieces together!**